Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L4	158	(anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5) near5 (bin\$3 stor\$4 flag\$4) near3 (region area pixels pels) near3 (around surround\$4 proximat\$3 border\$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/25 13:41
L5	48	"382".clas. and 4	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/25 13:42
S1	13	peterson near2 ingrid.in. hoff near2 (mike michael).in. wiley near2 jim. in.	US-PGPUB; USPAT	OR	OFF	2007/01/31 14:39
S2	4	"6268093".pn. "6373975".pn. "6701004".pn. "5965306".pn.	US-PGPUB; USPAT	OR	OFF	2006/12/27 18:45
S3	1	"20040091142"	US-PGPUB	OR	OFF	2007/01/31 17:04
S5	2480728	focus exposure illumination aperture coherence	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/17 10:09
S6	5708802	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/17 10:12
S7	997466	photomask lithograph\$3 semiconductor near mask pcb circuit near2 board reticle wafer	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:19
S8	11954984	different distinct many several plural\$4 var\$3 chang\$3 distinctive various numerous separate	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/17 10:17

S9	273699	S8 near3 S5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/17 10:19
S10	148789	S6 with S7	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/17 10:18
S11	7	(subtract\$3 tak\$3 adj away remov\$3) near3 (non-transient)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/17 17:40
S12	1	S9 and S10 and S11	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/17 10:20
S13	10220	S9 and S10	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON.	2007/01/17 10:22
S14	451	(subtract\$3 tak\$3 adj away remov\$3) near3 (hard near3 S6)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/17 17:43
S15	5	S13 and S14	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/17 10:25

S16	5708802	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR .	ON	2007/09/25 13:39
S17	17875	(non-transient hard enduring non-fleeting non-evanescent) near3 S16	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/18 14:30
S18	453	(subtract\$3 tak\$3 adj away remov\$3) near3 S17	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 11:59
S19	997466	photomask lithograph\$3 semiconductor near mask pcb circuit near2 board reticle wafer	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/17 17:44
S20	38	S19 near3 S16 and S18	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR .	ON	2007/01/17 17:44
S21	37975	(transient non-transient soft hard brief enduring fleeting non-fleeting evanescent non-evanescent) near3 S16	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/31 12:15
S22	4	("5308722"   "6421457").PN. OR ("6701004").URPN.	US-PGPUB; USPAT; USOCR	OR	OFF .	2007/01/18 14:24

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S23	5711627	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/18 14:30
S24	22954	(transient soft brief fleeting evanescent) near3 S23	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/18 15:06
S25	17897	(non-transient hard enduring non-fleeting non-evanescent) near3 S23	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 15:24
S26	21	(subtract\$3 tak\$3 adj away remov\$3) near3 S25 same S24	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR ,	ON	2007/01/18 14:46
S27	1580	S24 same S25	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/18 15:06
S28	6952	382/141-145,147,149,182,185.ccls. 348/87,131.ccls. 359/436,385.ccls. 356/401.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/18 15:08
S29	5711627	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/18 15:08

S30	22954	(transient soft brief fleeting evanescent) near3 S29	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON <sub>.</sub>	2007/01/18 15:08
S31	17897	(non-transient hard enduring non-fleeting non-evanescent) near3 S29	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/18 15:08
S32	1580	S30 same S31	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/18 15:08
S33	6	S32 and S28	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/18 15:10
S34	. 1	(transient non-transient soft hard brief enduring fleeting non-fleeting evanescent non-evanescent) and "6701004".pn.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/18 15:34
S35	5725702	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/31 12:15
S36	212	(transient non-transient soft hard brief enduring fleeting non-fleeting evanescent non-evanescent) near3 S35 and "382".clas.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:18
S37	1	("2004/0091142").URPN.	USPAT	OR .	OFF	2007/01/31 13:33

S38	4	("5308722"   "6421457").PN. OR ("6701004").URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/01/31 13:35
S39	6974	382/141-145,147,149,182,185.ccls. 348/87,131.ccls. 359/436,385.ccls. 356/401.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/31 14:40
S40	712	reference near3 compar\$3 and S39	US-PGPUB; USPAT	OR	ON	2007/09/20 15:53
541	5725702	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/31 15:19
S43	1001769	photomask lithograph\$3 semiconductor near mask pcb circuit near2 board reticle wafer	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/31 15:23
S44	144	reference near3 compar\$3 with S41 and S39 and S43 near3 S41	US-PGPUB; USPAT	OR	ON	2007/01/31 15:52
S47	1981	(bin binning) with region	US-PGPUB; USPAT	OR	ON	2007/01/31 15:54
S48	· 12	S39 and S47	US-PGPUB; USPAT	OR	ON	2007/01/31 15:56
S49	182	(high bright) with (low dark) with (filter\$3 remov\$3) with (pre-process\$3 preprocess\$3)	US-PGPUB; USPAT	OR	ON	2007/01/31 15:58
S50	1	S39 and S49	US-PGPUB; USPAT	OR	ON	2007/01/31 15:58
S51	29	"382".clas. and S49	US-PGPUB; USPAT	OR	ON	2007/01/31 16:03
S52	12091	(multiple many several array) near3 (CCD sensor detector) with pixel	US-PGPUB; USPAT	OR	ON	2007/01/31 16:04
S53	157	S39 and S52	US-PGPUB; USPAT	OR	ON	2007/01/31 16:13
S54	1225	flag\$3 with review\$3	US-PGPUB; USPAT	OR	ON	2007/01/31 16:38
S55	15	S39 and S54	US-PGPUB; USPAT	OR	ON	2007/01/31 16:44

S56	267	(remov\$3 filter\$3) with (high same low) near3 intensity	US-PGPUB; USPAT	OR	ON	2007/01/31 16:48
S57	28	"382".clas. and S56	US-PGPUB; USPAT	OR	ON	2007/01/31 16:45
S58	49	(threshold\$3) with (high same low) near3 intensity and "382".clas.	US-PGPUB; USPAT	OR	ON	2007/01/31 16:49
S59	9	(threshold\$3) with (high same low) near3 intensity and S39	US-PGPUB; USPAT	OR	ON	2007/01/31 16:50
S61	40	S58 not S59	US-PGPUB; USPAT	OR	ON	2007/01/31 16:51
S66	60928	"382".clas. S39	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/01/31 17:12
S67	246	(remov\$3 filter\$3 threshold\$3) near3 (dark same bright)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/31 17:13
S68	. 12	(remov\$3 filter\$3 threshold\$3) near3 (high same low) near3 (brightness lightness) and S66	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/31 17:13
S69	55	S67 and S66	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/31 17:18
S70	9	S69 and S39	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/01/31 17:18
S71	122	lithograph\$3 near7 aerial adj image	US-PGPUB; USPAT	OR	ON	2007/05/22 16:34
S72	2	aerial adj image same non-aerial adj image	US-PGPUB; USPAT	OR	ON	2007/05/22 16:35

S73	1	"20040091142"	US-PGPUB; USPAT	OR	ON	2007/05/22 16:37
S74 <sub>.</sub>	6009	(photomask photoreticle reticle mask) near3 (defect\$1 inspect\$3)	US-PGPUB; USPAT	OR	ON	2007/05/22 16:39
S76	5862607	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/05 16:15
S77	203	reticle near3 S76 and lithograph\$3 and aerial adj imag\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/05 16:16
S78	7191	382/141-145,147,149,182,185.ccls. 348/87,131.ccls. 359/436,385.ccls. 356/401.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 15:24
S79	27	S78 and S77	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 11:01
580	1197	aerial adj image adj measur\$6 adj system AIMS with (reticle mask)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 12:20
S81	5862607	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 11:12

S82	37029	S81 near3 (mask reticle)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 11:42
S83	54	S80 same S82	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR ·	ON	2007/06/06 11:45
S84	1	08/950620.app.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 11:45
S85	1037	aerial adj imag\$3 with (reticle mask)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ÖN	2007/06/06 11:50
S86	140	S85 same S82 not S83	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 11:50
S87	1	"5795688".pn.	USPAT	OR	OFF	2007/06/06 12:05
S88	1201	aerial adj imag\$3 adj measur\$6 adj system AIMS with (reticle mask)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON .	2007/06/06 12:20
S89	5862607	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 13:18

S90	39263	(transient non-transient soft hard brief enduring fleeting non-fleeting evanescent non-evanescent) near3 S89	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 15:51
S91	611729	photomask semiconductor near mask reticle mask	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/25 13:38
S93	18494	(non-transient hard enduring non-fleeting non-evanescent) near3 S89	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:26
S94	526	S93 near7 S91	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:27
S95	237	S93 near7 S91 with (non-aerial print\$3 project\$3 etch\$3)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:30
S96	0	S93 near7 S91 with (non-aerial)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:28
S97	7191	382/141-145,147,149,182,185.ccls. 348/87,131.ccls. 359/436,385.ccls. 356/401.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:28

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S98	1	S95 and S97	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:29
S99	30	S93 and S97	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 13:30
S10 0	7191	382/141-145,147,149,182,185.ccls. 348/87,131.ccls. 359/436,385.ccls. 356/401.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/06/06 15:24
S10 1	5862607	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 15:24
S10 2	18495	(non-transient hard enduring non-fleeting non-evanescent) near3 S101	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 15:28
S10 3	30	S102 and S100	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 15:25
S10 4	92	S100 and (pinhole pindot extrusion) same (mask reticle photomask)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/06/06 15:28
S10 6	1056	mask adj layout	USPAT	OR	OFF	2007/09/20 11:58

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S10 8	5981851	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 11:59
S10 9	19021	(non-transient hard enduring non-fleeting non-evanescent) near3 S108	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 11:59
S11 0	496	(subtract\$3 tak\$3 adj away remov\$3) near3 S109	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 11:59
S11 1	7372	382/141-145,147,149,182,185.ccls. 348/87,131.ccls. 359/436,385.ccls. 356/401.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 15:18
S11 2	3	S110 and S111	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 12:00
S11 3	3616	aerial adj imag\$3	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 15:18
S11 4	132689	(transient with non-transient soft with hard brief with enduring fleeting with non-fleeting evanescent with non-evanescent)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 15:59

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S11 5	5304	(determin\$3 locat\$4 find\$4 flag\$4 extract\$3) with S114	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 16:00
S11 6	7372	382/141-145,147,149,182,185.ccls. 348/87,131.ccls. 359/436,385.ccls. 356/401.ccls.	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	OFF	2007/09/20 15:53
S11 7	4	S116 and S115	US-PGPUB; USPAT	OR	ON	2007/09/20 15:53
S11 8	136	(determin\$3 locat\$4 find\$4 flag\$4 extract\$3) with S114 same (reticle wafer mask photomask semiconductor)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 15:58
S11 9	5981851	anomaly defect imperfection blemish crack deformity error fault flaw hole irregular\$7 scratch contamina\$5	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 16:00
S12 0	1365	(transient near3 S119 with non-transient near3 S119 soft near3 S119 with hard near3 S119 brief near3 S119 with enduring near3 S119 fleeting near3 S119 with non-fleeting near3 S119 evanescent near3 S119 with non-evanescent near3 S119)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 16:00
S12 1	14	(determin\$3 locat\$4 find\$4 flag\$4 extract\$3) with S120 same (reticle wafer mask photomask semiconductor)	US-PGPUB; USPAT; USOCR; FPRS; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2007/09/20 16:04